



500.41374CX2

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): S. KANNO, et al  
Serial No.: 10/658,281  
Filed: September 10, 2003  
For: WAFER STAGE FOR PROCESSING APPARATUS AND  
WAFER PROCESSING METHOD  
Group: 3742  
Examiner: S. Fuqua

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

October 5, 2004

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated May 5, 2004, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.